

**Notice of References Cited**

Application/Control No.  
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Applicant(s)/Patent Under  
Reexamination  
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**NON-PATENT DOCUMENTS**

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	U	Komatsu et al., "A new auto-focus method in critical dimension measurement SEM," IEEE 1997, pages 202-207.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.